



April 9, 2004

To: Commissioner for Patents
 P.O.Box 1450
 Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
 28 Davis Avenue
 Poughkeepsie, N.Y. 12603

Subject:	Serial No. 10/786,807 02/25/04
	H.M. Chen et al.
	METHOD FOR IMPROVING SEMICONDUCTOR WAFER TEST ACCURACY

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
 In An Application.

The following Patents and/or Publications are submitted to
 comply with the duty of disclosure under CFR 1.97-1.99 and
 37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
 deposited with the United States Postal Service as first class
 mail in an envelope addressed to: Commissioner for Patents,
 P.O. Box 1450, Alexandria, VA 22313-1450, on April 12, 2004.

Stephen B. Ackerman, Reg.# 37761

Signature/Date S. B. Ackerman 4/12/04

U.S. Patent 6,291,268 to Ho, "Low Cost Method of Testing a Cavity-Up BGA Substrate," discloses a method for testing a BGA substrate.

U.S. Patent 6,162,652 to Dass et al., "Process for Sort Testing C4 Bumped Wafers," describes a method of cleaning and testing bumped wafers.

U.S. Patent 6,143,668 to Dass et al., "KLXX Technology with Integrated Passivation Process, Probe Geometry and Probing Process," describes a wafer testing method utilizing cleaning of bond pads prior to testing.

Sincerely,



Stephen B. Ackerman,
Reg. No. 37761



Form PTO-1449

101- INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

Doctor Hummer (Specimen)

MEG-02-005

Section Number

101786, 807

Locality

H.M. Chen et al.

Elmer D. St.

02/25/04 Draw in Unit

APR 15 200

U. S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

OTHER DOCUMENTS (Including Author, Title, Date, Portion or Pages, Etc.)

БИБЛИО

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.